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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/648,883	08/27/2003	Satoru Yamada	16995	4882	
23389	7590 04/21/2005		EXAM	EXAMINER	
SCULLY SCOTT MURPHY & PRESSER, PC 400 GARDEN CITY PLAZA			QUINTO,	QUINTO, KEVIN V	
SUITE 300	VCII I FLAZA	·	ART UNIT	PAPER NUMBER	
GARDEN CI	TY, NY 11530		2826		

DATE MAILED: 04/21/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)				
	10/648,883	YAMADA ET AL.				
Office Action Summary	Examiner	Art Unit				
	Kevin Quinto	2826				
The MAILING DATE of this communication ap Period for Reply	pears on the cover sheet with the	correspondence addres	S			
A SHORTENED STATUTORY PERIOD FOR REPL THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1. after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a rep- if NO period for reply is specified above, the maximum statutory period  - Failure to reply within the set or extended period for reply will, by statut Any reply received by the Office later than three months after the mailinearned patent term adjustment. See 37 CFR 1.704(b).	136(a). In no event, however, may a reply be to bly within the statutory minimum of thirty (30) da will apply and will expire SIX (6) MONTHS from e, cause the application to become ABANDON	imely filed  sys will be considered timely.  the mailing date of this commur  ED (35 U.S.C. § 133).	nication.			
Status						
1)⊠ Responsive to communication(s) filed on 10 J	lanuary 2005.					
2a) This action is <b>FINAL</b> . 2b) ⊠ Thi	☐ This action is <b>FINAL</b> . 2b)☑ This action is non-final.					
Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11, 453 O.G. 213.						
Disposition of Claims						
4)⊠ Claim(s) <u>1-11</u> is/are pending in the application	1.					
4a) Of the above claim(s) is/are withdra	wn from consideration.					
5) Claim(s) is/are allowed.						
6) Claim(s) 1-5,8 and 10 is/are rejected.	·	•				
7)⊠ Claim(s) <u>6,7,9 and 11</u> is/are objected to. 8)□ Claim(s) are subject to restriction and/o	or election requirement					
are subject to restriction and	or ciccion requirement.					
Application Papers						
9)⊠ The specification is objected to by the Examin	er.					
0)☐ The drawing(s) filed on is/are: a)☐ accepted or b)☐ objected to by the Examiner.						
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).						
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).  11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.						
11) I he oath or declaration is objected to by the E	xaminer. Note the attached Offic	e Action or form PTO-1	52.			
Priority under 35 U.S.C. § 119						
<ul> <li>12) Acknowledgment is made of a claim for foreign</li> <li>a) All b) Some * c) None of:</li> <li>1. Certified copies of the priority document</li> </ul>		a)-(d) or (f).				
2. Certified copies of the priority document		tion No				
3. Copies of the certified copies of the prior			е			
application from the International Burea	•	ou iii iiii o i uu o ii u o iu o				
* See the attached detailed Office action for a list		ed.				
Attachment(s)	<b>4</b> ,□	(PTO 442)				
1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948)	4) 🔲 Interview Summar Paper No(s)/Mail D	Date				
Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date	5) Notice of Informal 6) Other:	Patent Application (PTO-152)	1			

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#### **DETAILED ACTION**

#### Response to Arguments

1. Applicant's arguments with respect to claims 1-11 have been considered but are most in view of the new ground(s) of rejection.

## Specification

- 2. The title of the invention is not descriptive. A new title is required that is clearly indicative of the invention to which the claims are directed.
- 3. This objection was made in the previous Office action but it has not been addressed by the applicant.

### Claim Objections

4. Claims 9 and 11 are objected to because of the following informalities: the phrases "having the lowest Fermi level is disposed" (in claims 9 and 11) and "having the highest Fermi level is disposed" (in claim 11) appear to be grammatically incorrect.

Appropriate correction is required.

# Claim Rejections - 35 USC § 103

- 5. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the

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invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

- 6. Claims 1-5, 8, and 10 are rejected under 35 U.S.C. 103(a) as being unpatentable over Schwalke (USPN 5,932,919) in view of Takashima et al. (USPN 5,953,246) and further in view of Shau (USPN 6,216,246 B1) and further in view of Noble et al. (USPN 6,573,169 B2).
- 7. In reference to claims 1-4 and 8, Schwalke (USPN 5,932,919) discloses a similar device and its process of fabrication. Figure 1H of Schwalke discloses a low threshold voltage CMOS transistor pair for use in a DRAM device. The transistor on the left is an n-channel transistor with an n-type gate (26). The transistor on the right is a p-channel transistor with a gate (30) with both n-type and p-type doping. This gate (30) is mostly n-type (column 3, lines 1-6) with a higher than average concentration achieved by ion implantation (column 2, lines 54-56). Since p-type materials have Fermi levels near the valence band and n-type materials have Fermi levels near the conduction band, it is understood that the gate (30) for the p-channel transistor has a Fermi level lower than that of the gate (26) for the n-channel transistor by virtue of the combination of the ntype and p-type impurities within its gate (30) when compared to the strictly n-type gate (26) of the n-channel transistor. Schwalke does not disclose a third transistor with a ptype polysilicon gate having a low Fermi level. However the use of such transistors in a DRAM is well known in the art. Takashima et al. (USPN 5,953,246, hereinafter referred to as the "Takashima" reference) discloses an n-channel transistor with a p-type gate. Takashima discloses that such a gate allows the transistor to have a high threshold voltage (column 14, lines 17-21). Furthermore, Shau (USPN 6,216,246 B1) discloses

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that it is well known in the art that memory transistors have a higher threshold voltage than that of the peripheral circuitry for the benefits of higher voltage tolerance, leakage current reduction, and high performance peripheral logic circuitry (column 1, lines 41-47). In view of Shau and Takashima, it would therefore be obvious to use an n-channel transistor with a p-type gate. Takashima does not disclose the use of a polysilicon gate material for the p-type gate but the use of polysilicon as a gate material is well known in the art. Noble et al. (USPN 6,573,169 B2, hereinafter referred to as the "Noble" reference) discloses that the use of a polysilicon gate in a transistor leads to a more reliable device with superior drains and sources (column 1, lines 50-54). In view of Noble, it would therefore be obvious to use polysilicon as the gate material in order to attain the benefit of a more reliable transistor.

- 8. With regard to claim 5, Schwalke discloses a method of fabrication which meets these limitations regarding the masks (column 2, lines 52-67 and column 3, 25-33).
- 9. In reference to claim 10, the limitation "wherein the concentration of the p type impurity that is injected into the first N surface channel is reduced such that a pn junction leak current is reduced" has no patentable weight since a structural limitation has not been described. Therefore claim 10 is not patentable over the Schwalke, Takashima, Shau, and Noble references.

Allowable Subject Matter

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10. Claims 6 and 7 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

11. The following is a statement of reasons for the indication of allowable subject matter: the examiner is unaware of any prior art which suggests or renders obvious a method of fabricating a semiconductor device having a first p-type polysilicon gate at a first Fermi level, a first n-type polysilicon gate at a higher Fermi level than the first p-type polysilicon gate, and a second n-type polysilicon gate with both n-type and p-type doping which has a Fermi level that is between the first p-type polysilicon gate and the first n-type polysilicon gate where the dopants (both n-type and p-type) of the second n-type polysilicon gate are simultaneously activated.

#### Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Kevin Quinto whose telephone number is (571) 272-1920. The examiner can normally be reached on M-F 8AM-5PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nathan Flynn can be reached on (571) 272-1915. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

**KVQ** 

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